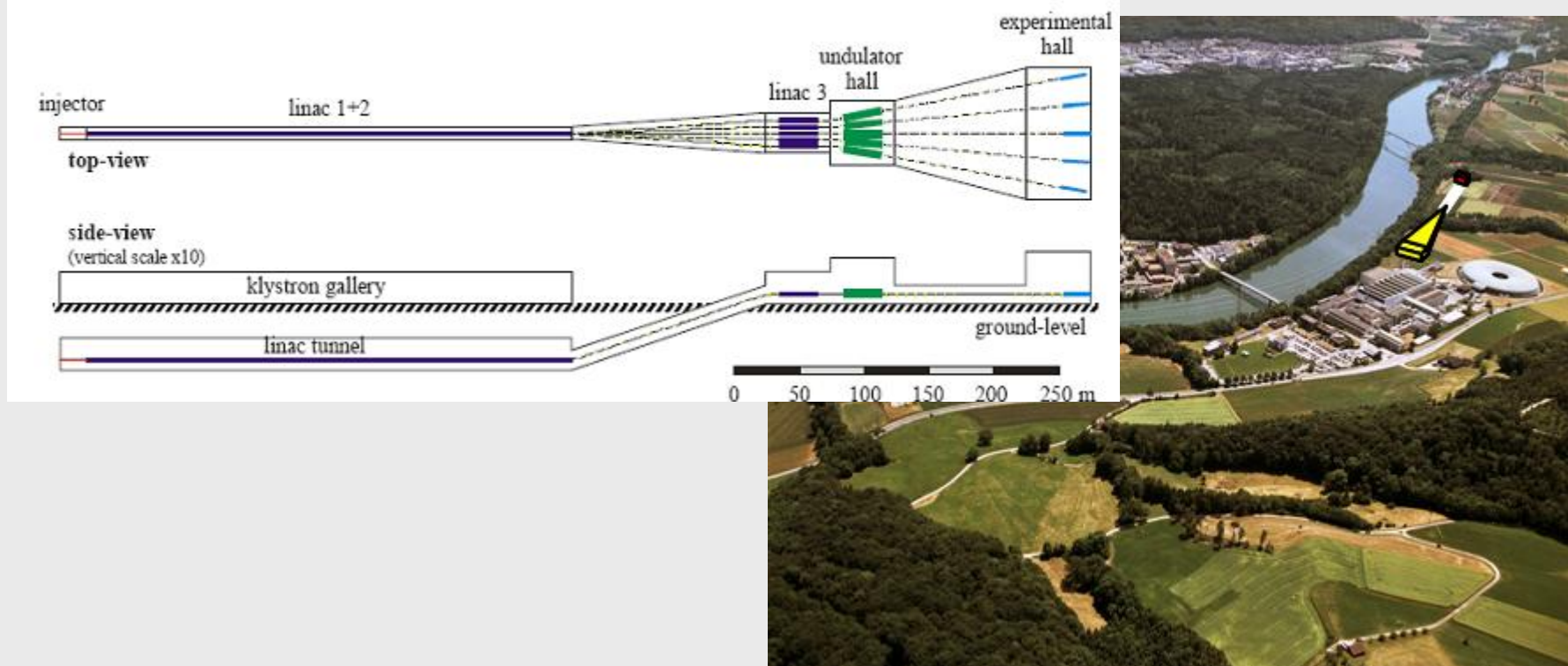
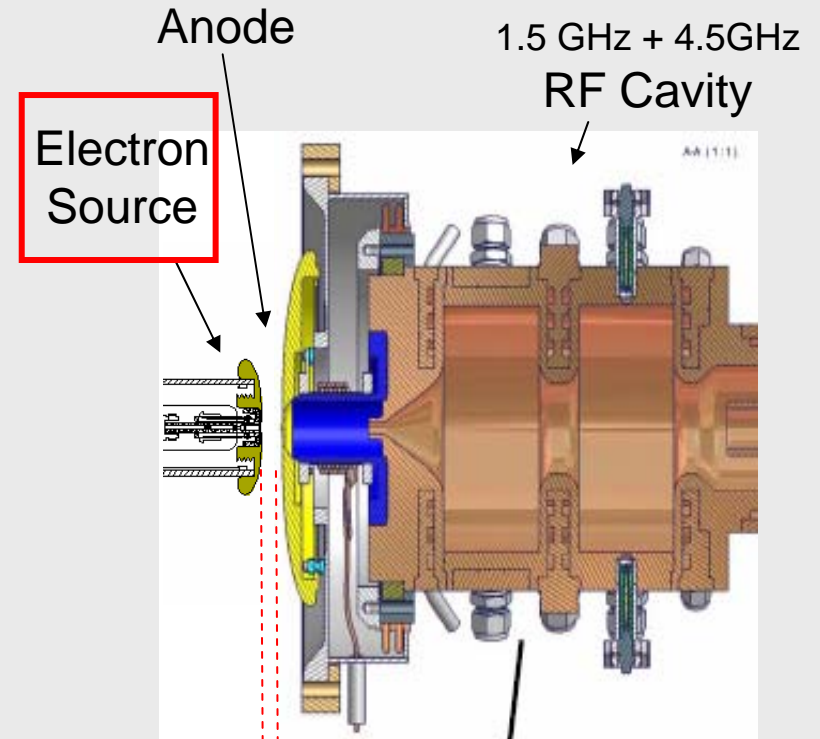
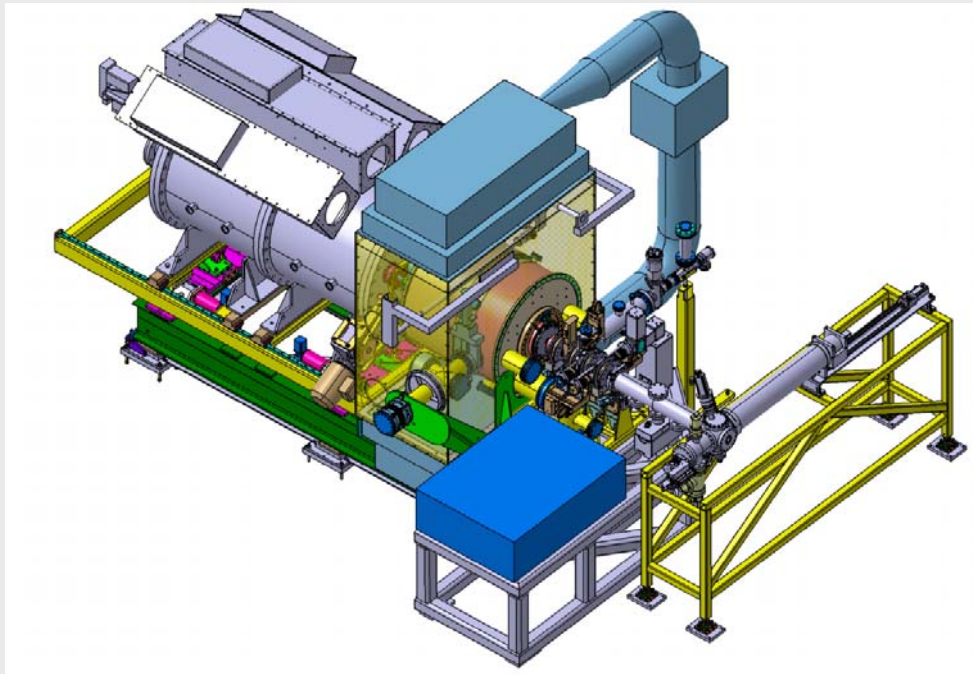


Field Emission Electron Sources - FEL Application



PSI – FEL Project : $0.1\text{nm} < \lambda < 10\text{nm};$
 10-100fs Pulses
 10Hz
 Compact Machine < 800 m

Expected Commissioning ~ 2016



Minimum Peak Current (A)	5.5
Normalized Slice Emittance (m.rad)	$5 \cdot 10^{-8}$
Bunch Length, rms (ps)	15
Energy at Gun Exit (MeV)	4
Repetition rate (Hz)	10

Pulsed Voltage

1MV in 200ns

4mm Gap

10 Hz

250 MV/m

Ultimate limit in Accelerators: Thermal emittance of the Electron Source

$$\varepsilon_{n,rms} = \frac{r}{2} \sqrt{\frac{2E_{kin}}{3mc^2}}$$

Size of the produced
Electron Beam

Thermal Agitation
of produced electrons

Goal : Emittance < $5 \cdot 10^{-8}$ m.rad

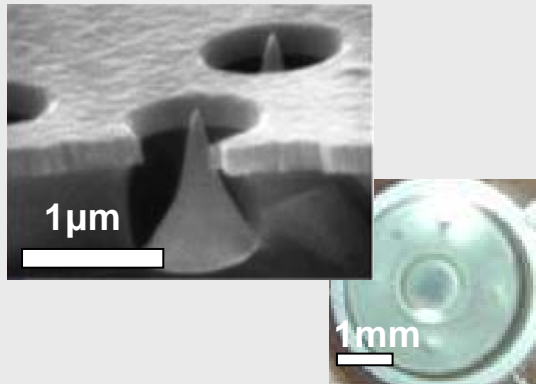
*Uniform Beam over r
+ Maxwell Distribution*

Field Emission requires High Field: $F_{\text{Surface}} > 3 \text{ GV} / \text{m}$



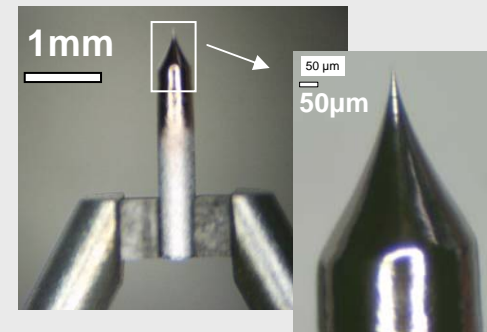
Field Enhancement with **Tip Effect**

Field Emitters Arrays (FEAs)



Microelectronic Techniques
Thin Film Deposition

Needle Cathode

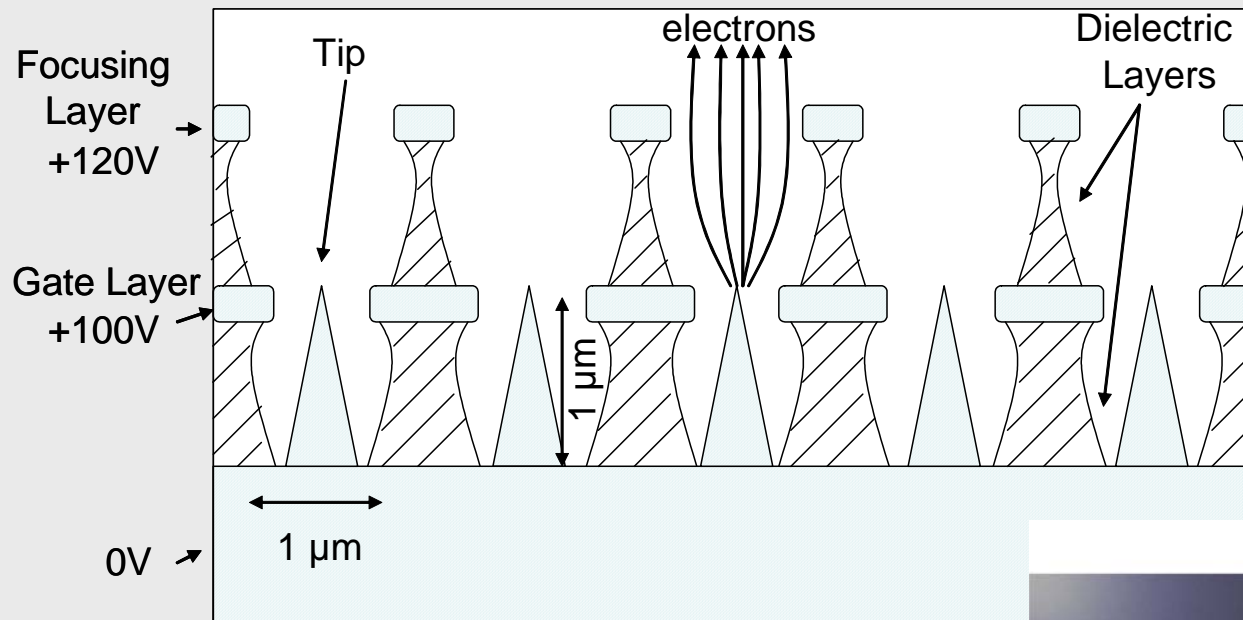


Etched Wire

Field Emitters Arrays (FEA)

Electron Sources

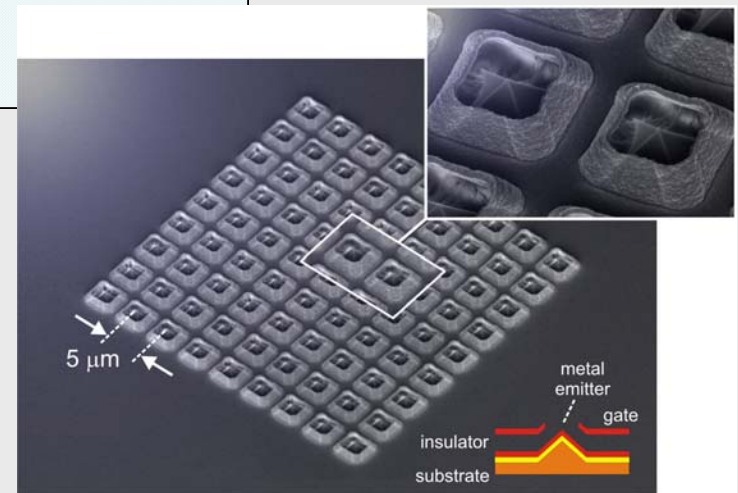
Principle of FEAs:

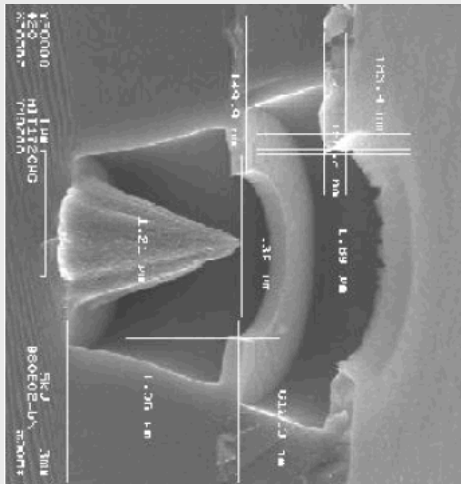


FEA's Characteristics:

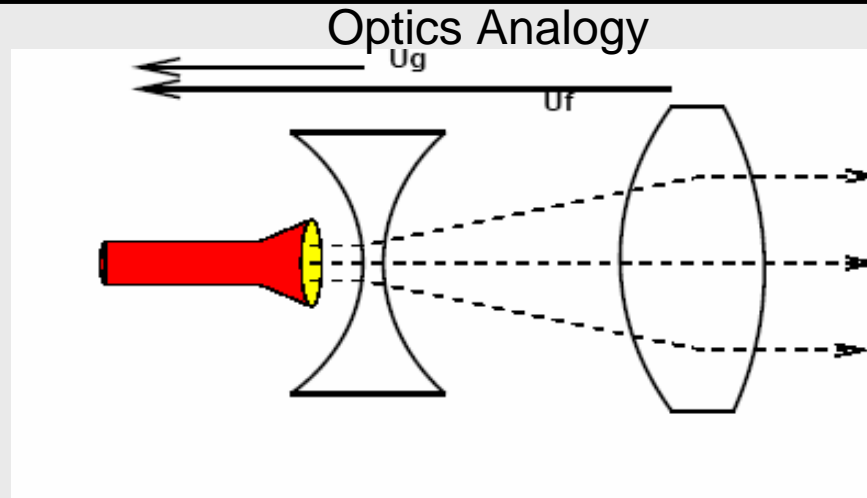
$10'000$ Tips / FEA
 $R_{tip} \sim 20 - 100\text{nm}$
 $\varnothing_{FEA} < 1\text{mm}$

 Typical $I_{FEA} < 1\text{mA}$



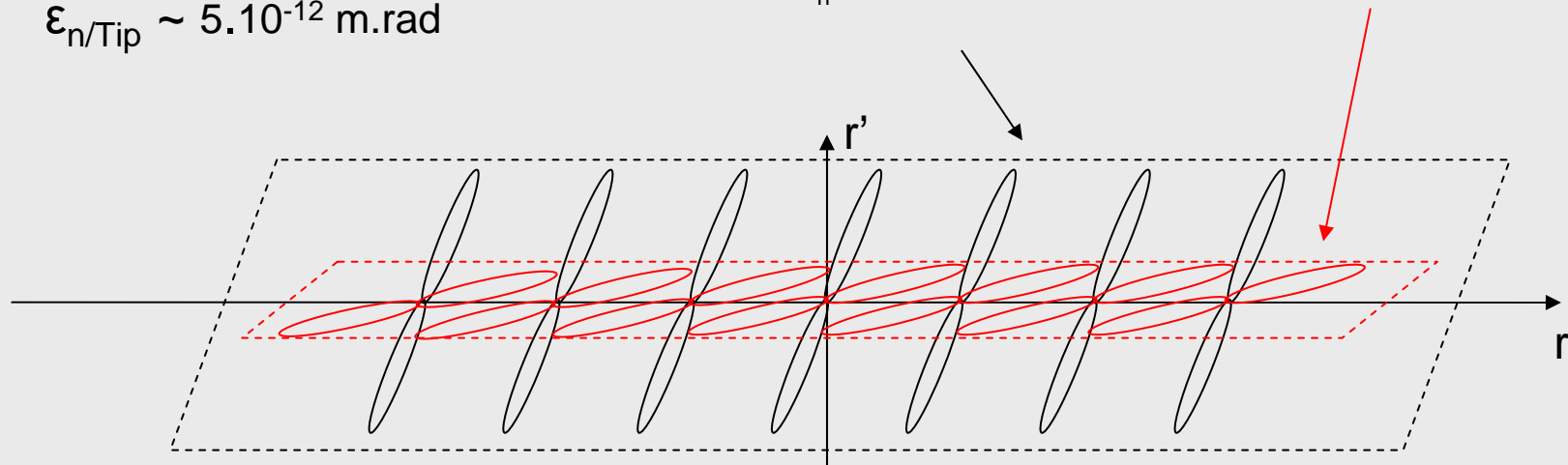


Thermal Emittance / Tip
 $r \sim 15\text{nm}$; $E_{\text{kin}} \sim 300\text{meV}$
 $\epsilon_{n/\text{Tip}} \sim 5 \cdot 10^{-12} \text{ m.rad}$



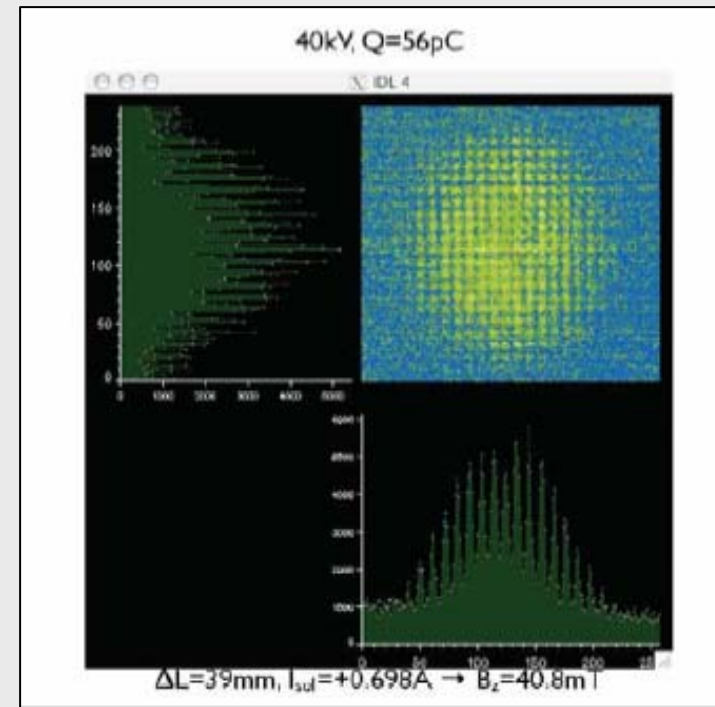
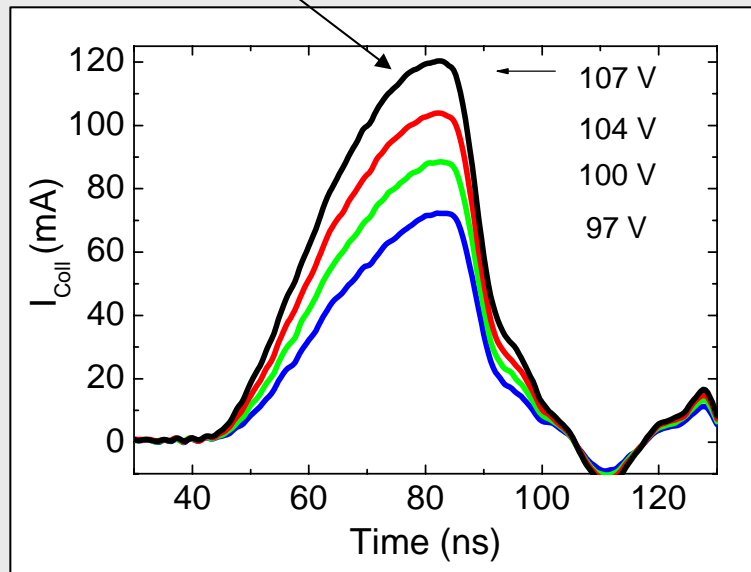
Initially
 $\epsilon_n \sim 2 \cdot 10^{-6} \text{ m.rad}$

After Focusing
 $\epsilon_n < 10^{-7} \text{ m.rad}$



120 mA (Pulses of 30ns at 10HZ)

(Commercial Device)

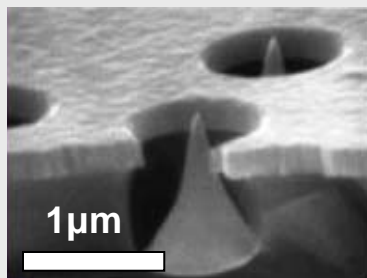


Projected Emittance **Single Gated FEA:**

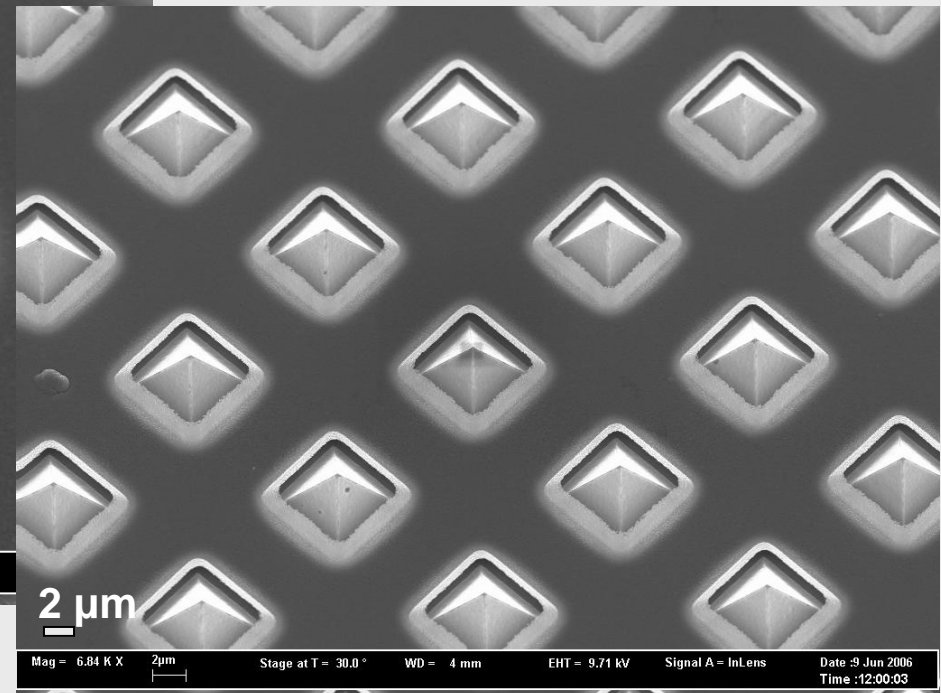
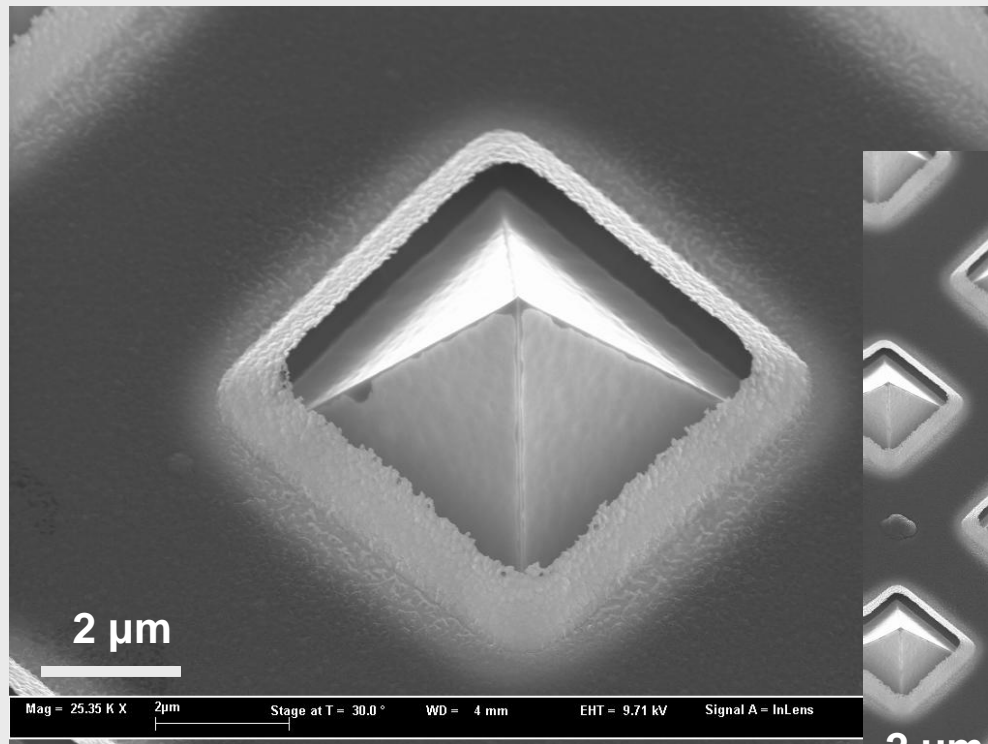
$$\epsilon_n \sim 2 \cdot 10^{-6} \text{ m.rad at 40 keV}$$

Source: S.C. Leemann

50000 Tips
 $\varnothing = 1 \text{ mm}$



Pyramid Shape – PSI FEA

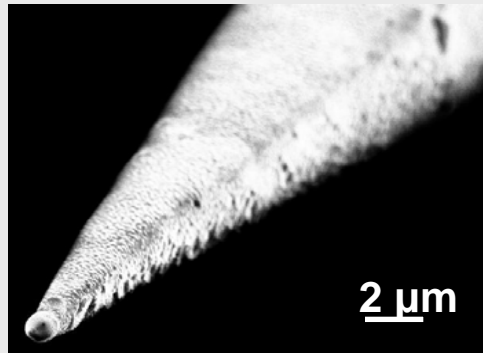


Source: E. Kirk

- Mo Tips (Field Enhancement Factor: $\langle \beta \rangle \sim 90$)
- Metallic wafer

Needle Cathode

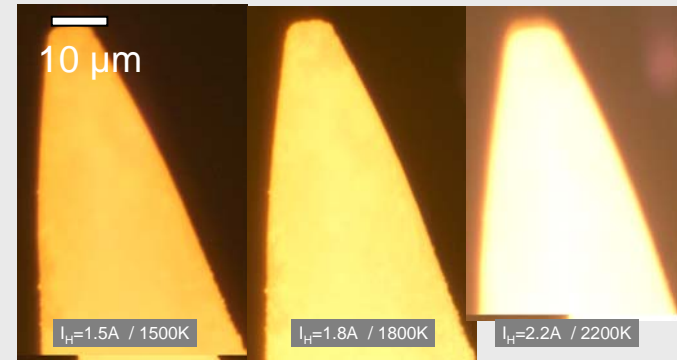
Electron Source



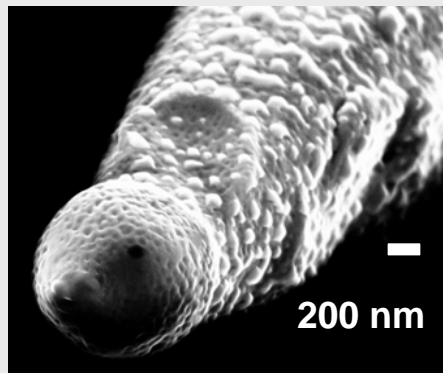
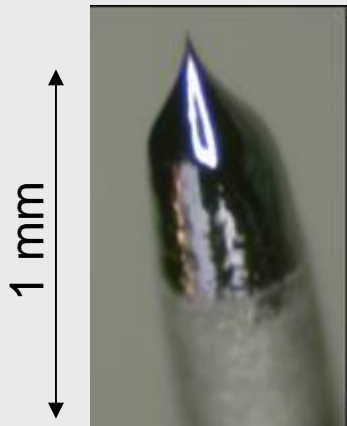
⇒ ZrC robust, $\Phi_{\text{ZrC}} \sim 4 \text{ eV}$

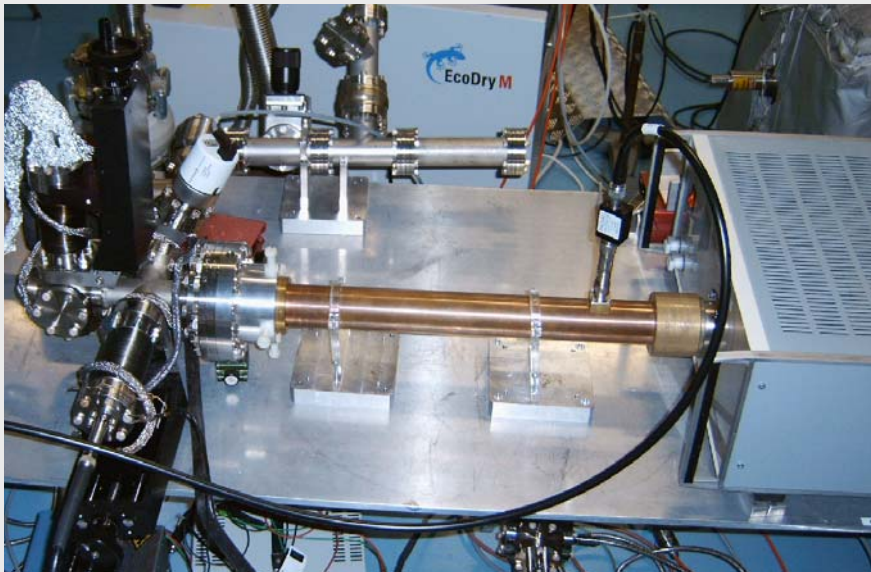
⇒ Possibility of Faceting the Tip

$r_{\text{apex}} \sim 1 \text{ to } 5 \mu\text{m}$



⇒ Required Operating Voltage
 $V_{\text{Tip}} > 10 \text{ kV}$

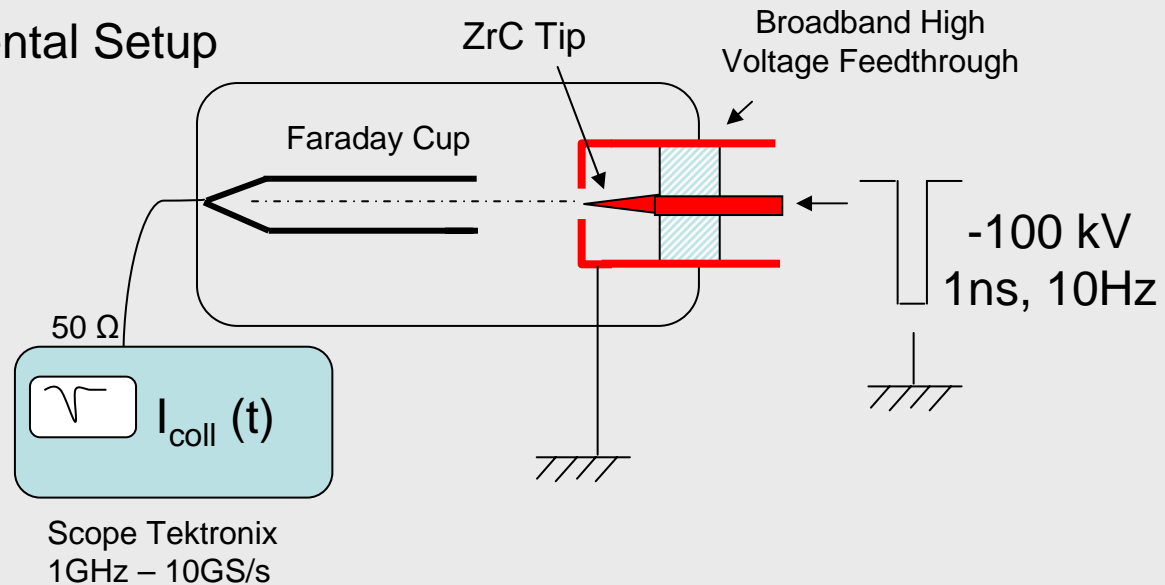
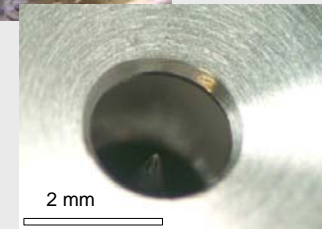


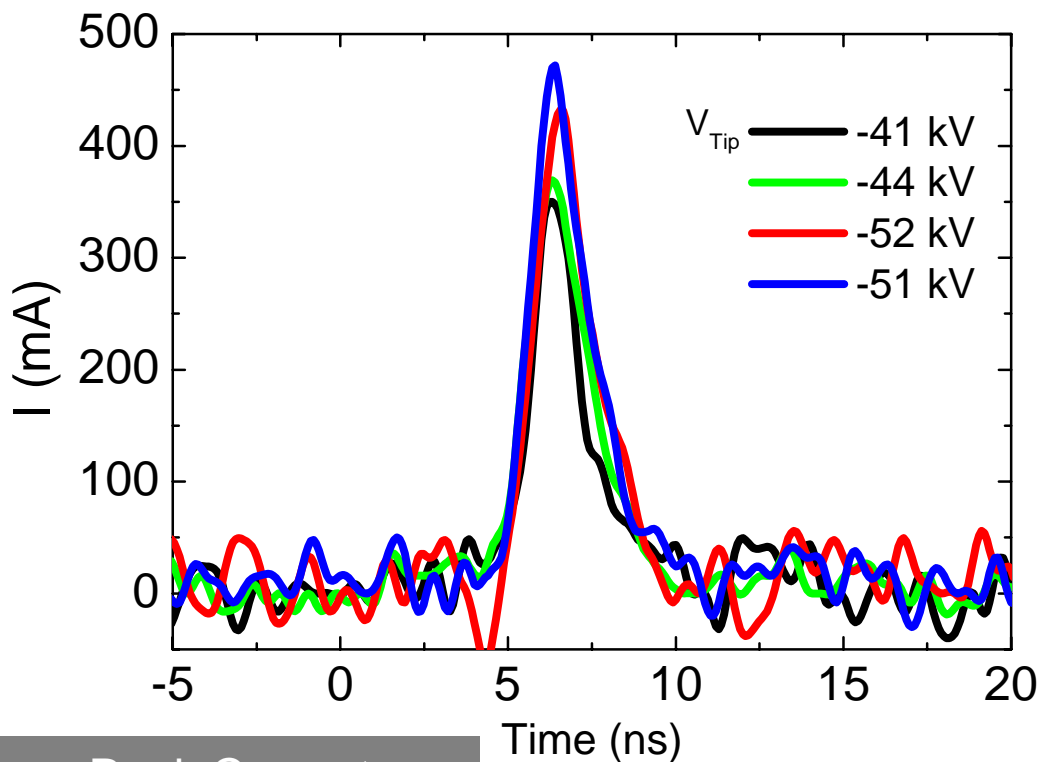


Experimental Setup

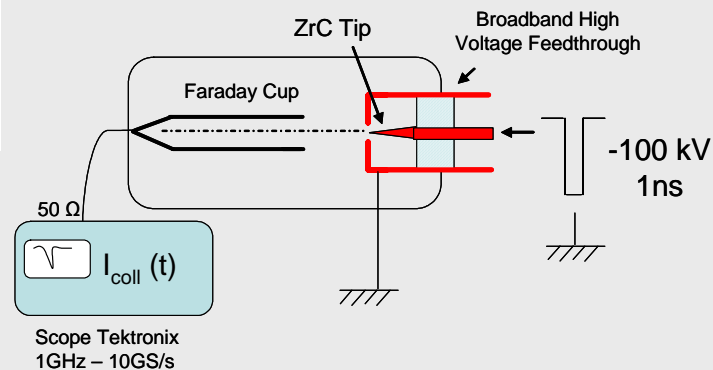
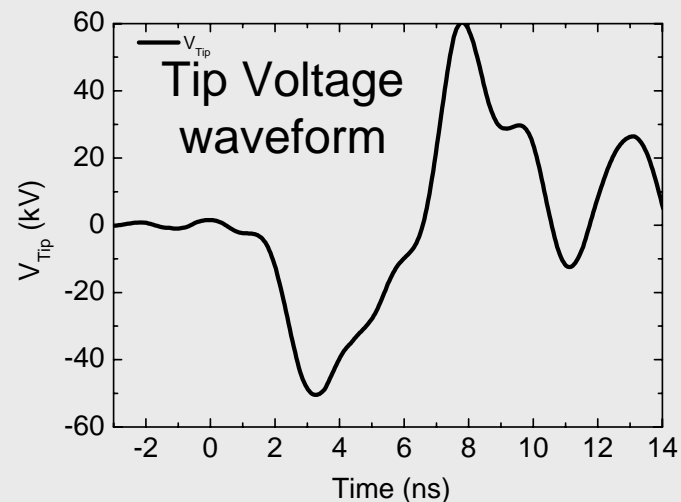


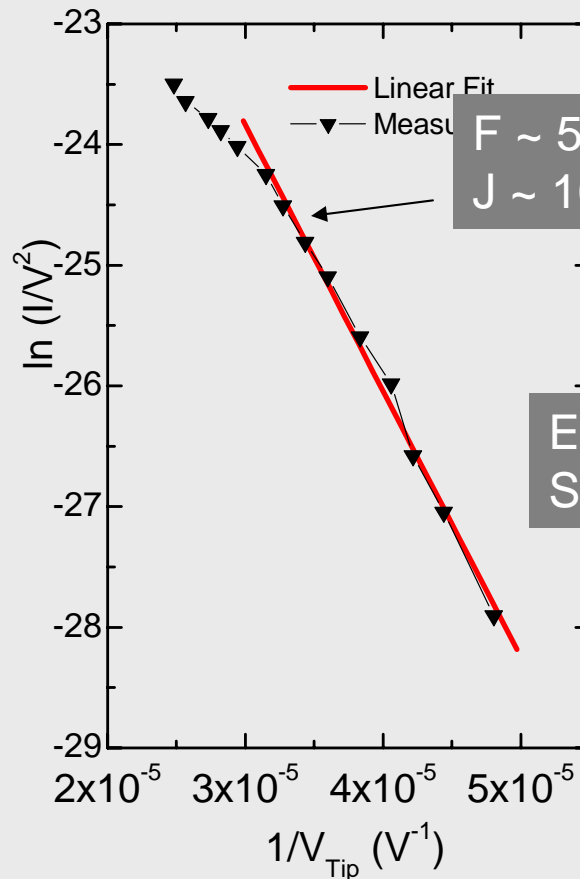
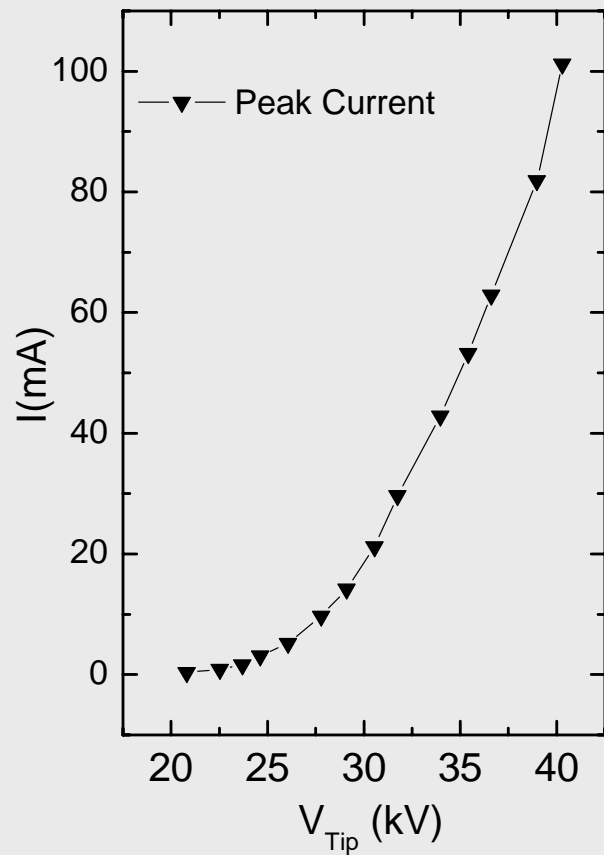
1GHz Feedthrough





Peak Current
By Field Emission
~ 500 mA

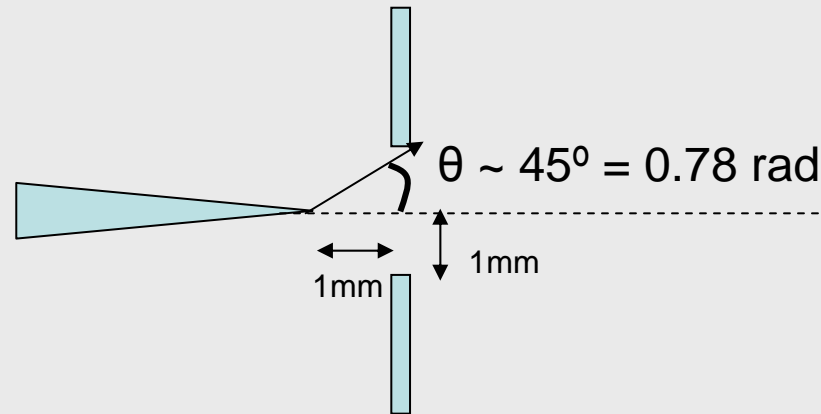
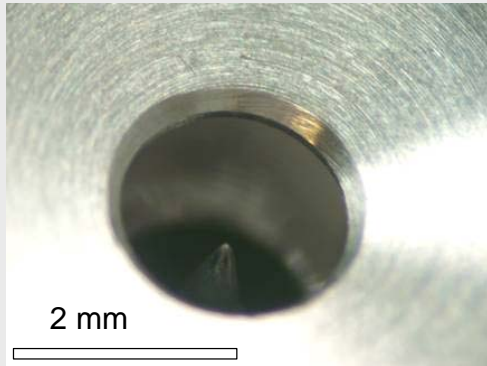




Emitting Area:
 $S \sim 12000 \text{ nm}^2$ ($\varnothing \sim 120 \text{ nm}$)

$$\ln\left(\frac{I}{V^2}\right) = -p\left(\frac{1}{V}\right) + m$$

ZrC Tip, Gate 2mm
 Voltage Pulses: 1ns at 10Hz
 $\Phi_{\text{ZrC}} \sim 3.5 \text{ eV}$, 10^{-9} Torr



Measure 1
 $S \sim 12000 \text{ nm}^2$
 $\varnothing_{\text{Beam}} \sim 125 \text{ nm}$
 $\beta = 192000 \text{ m}^{-1}$
 $r_{\text{apex}} \sim 1/(5\beta) \sim 1 \mu\text{m}$

$\epsilon_n \sim r_{\text{beam}} \cdot \theta \sim 62 \text{ nm} \cdot 0.78 \text{ rad} \sim 5 \cdot 10^{-8} \text{ m} \cdot \text{rad}$

$B_{\text{Max}} = \frac{I_{\text{Max}}}{\epsilon_n^2} \sim 10^{14} \text{ A} \cdot \text{m}^{-2} \cdot \text{rad}^{-2}$

Needle Cathode Beam: Attractive but too long bunches (ns)

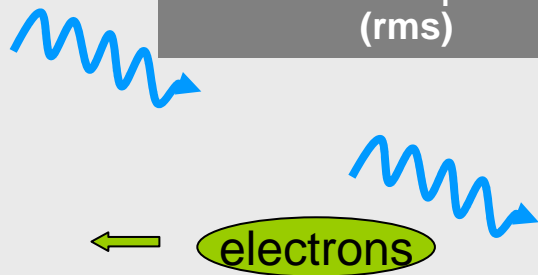
How to modulate the emission in the ps range ?

Laser assisted field emission (Photo-Field Emission)

(ref. M. Boussoukaya et. al. , NIM A 264, 131-134, 1988)

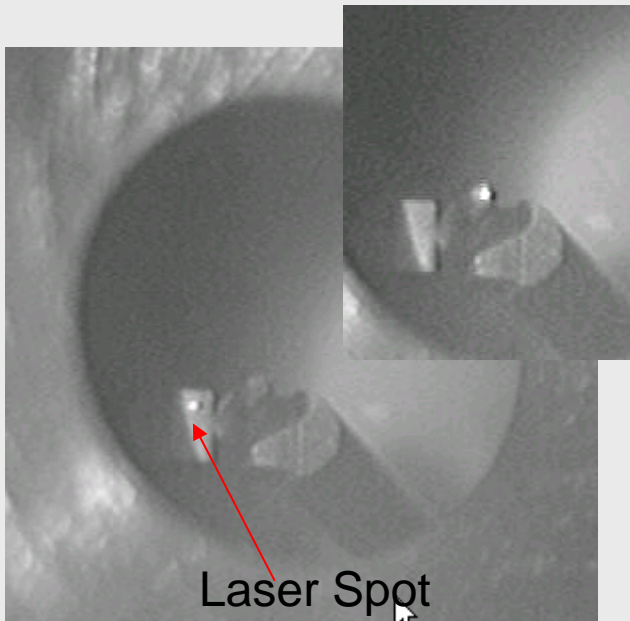
Combination of Field Emission and
Photoemission

Nd:VAN Laser:
11 μ J, 16ps (rms)
266nm, 30Hz
Spot Radius $\sigma_r \sim 100 \mu\text{m}$
(rms)

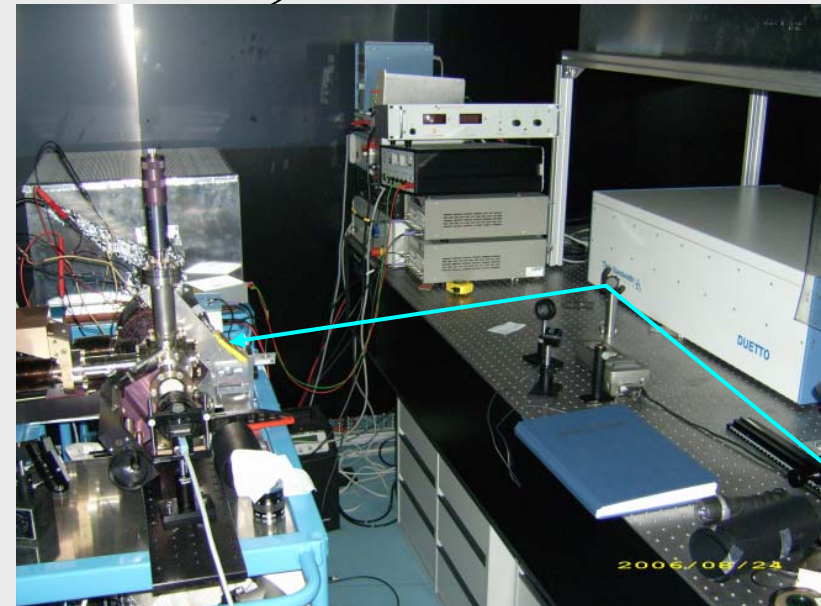


Tip Radius < 100 μm

$\varnothing \sim 4\text{mm}$



Laser Spot
(off axis): $\varnothing \sim 100 \mu\text{m}$

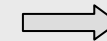


PSI FEL - R. Ganter

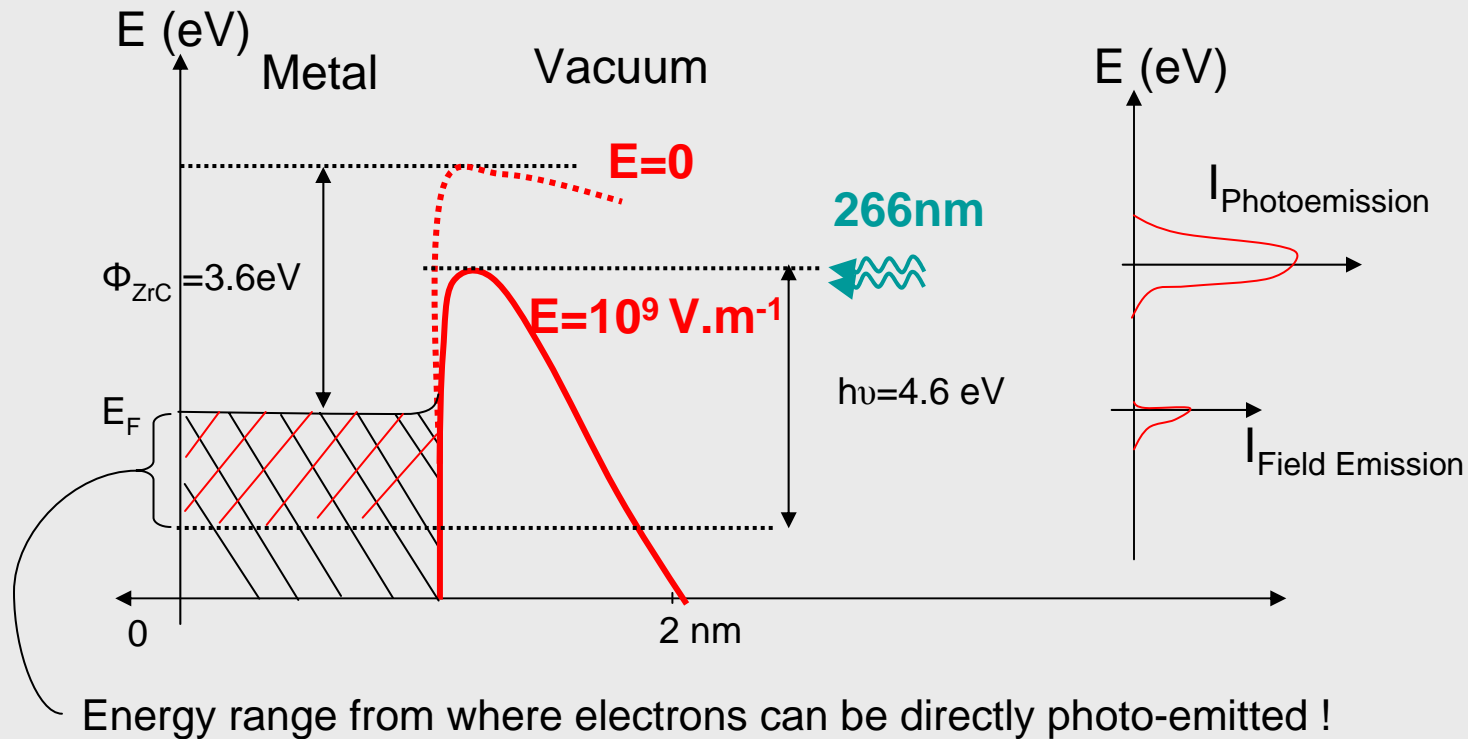
Schottky Effect

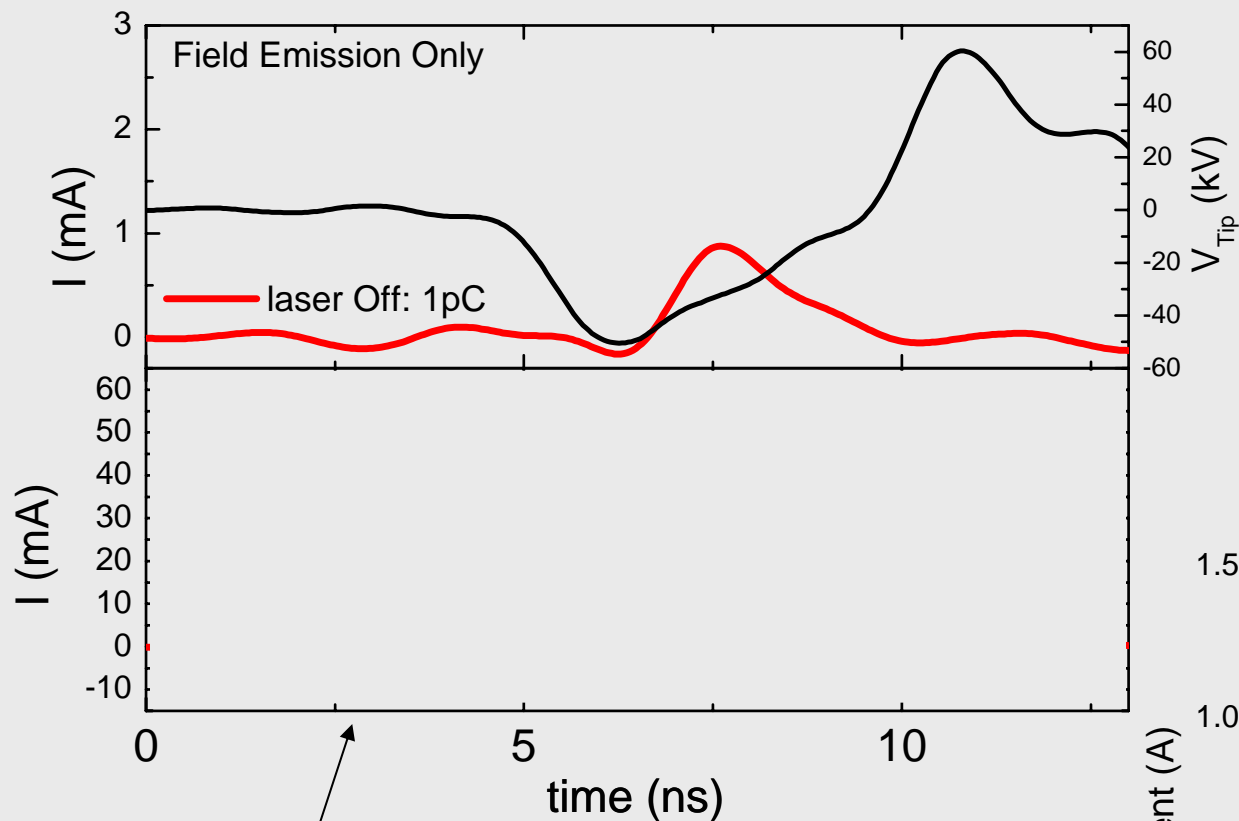


Larger Electron Reservoir
for Photoemission



Higher Quantum
Efficiency

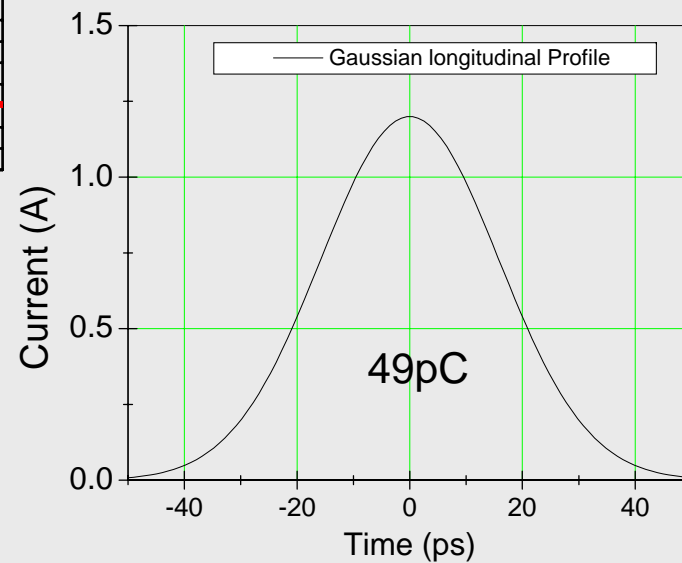


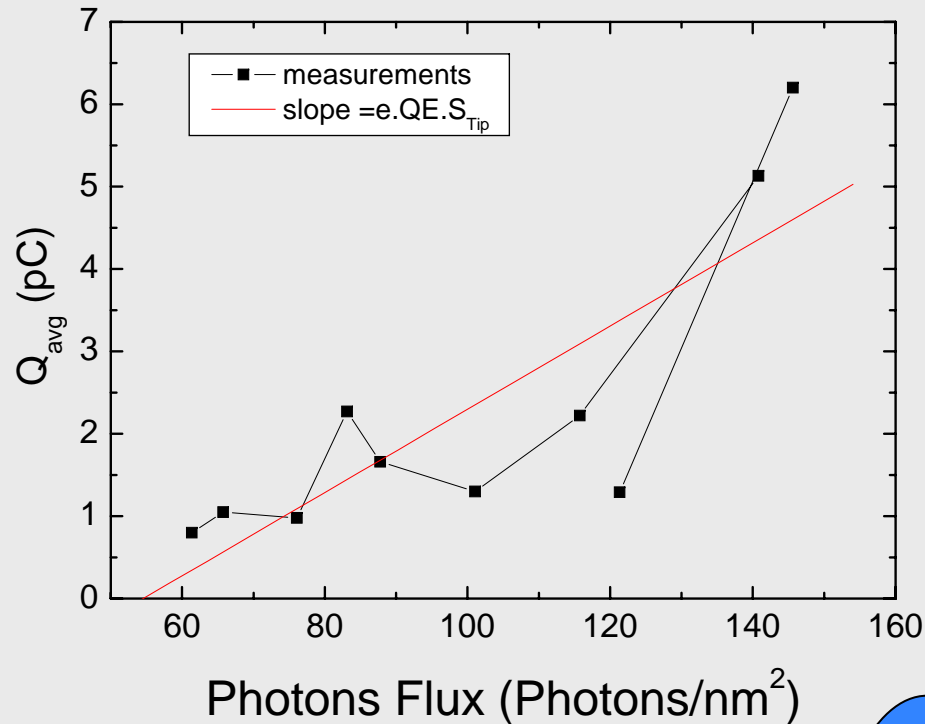


2 μ J at 266nm
49pC
Q.E. > 10⁻⁴

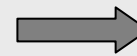
Limited by Scope Bandwidth (<1GHz)

Laser: 2 μ J / $\sigma_z=16$ ps /
 $\sigma_r=75\mu$ m / 30Hz / 266nm
ZrC tip / $V_{Tip}=-51$ kV

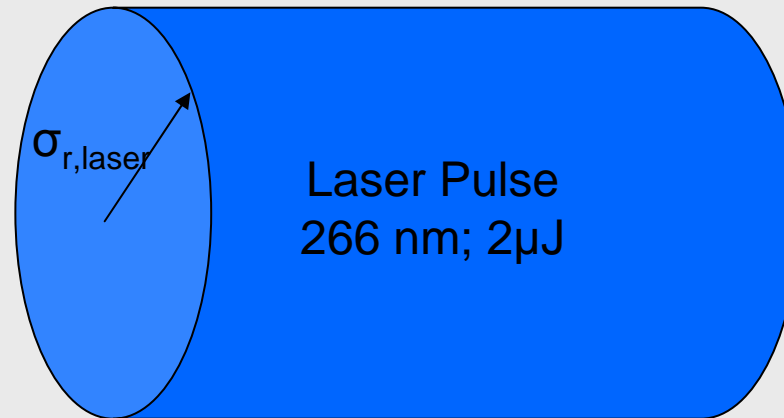
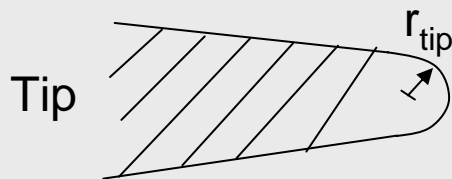


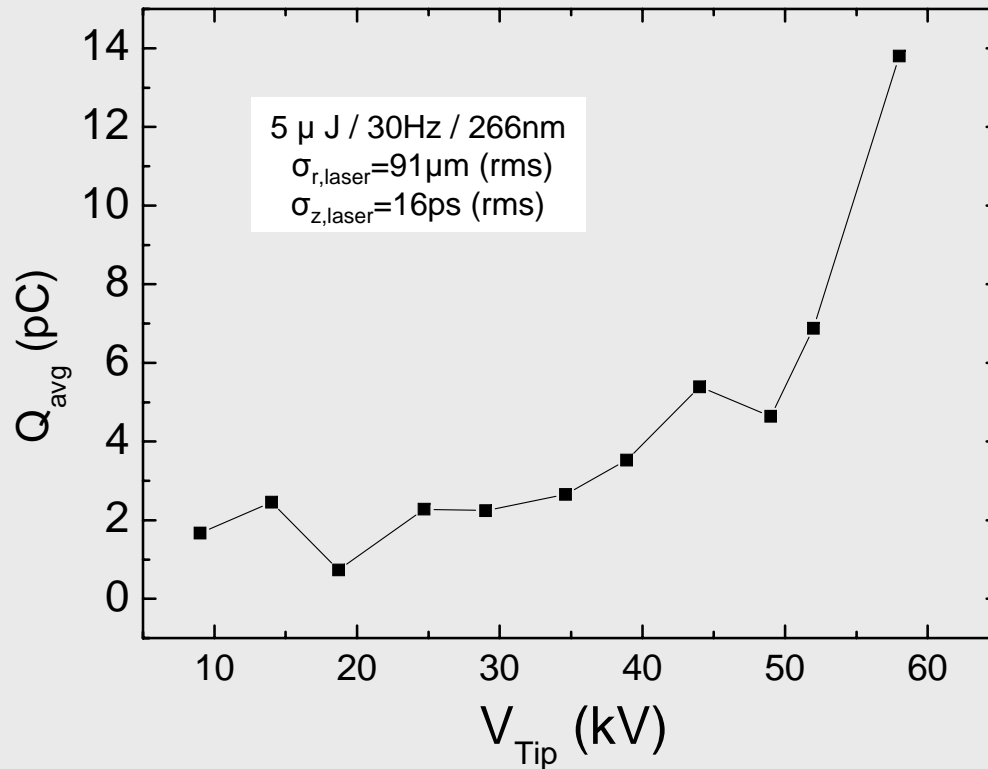


How many photons intercepted by Tip ?

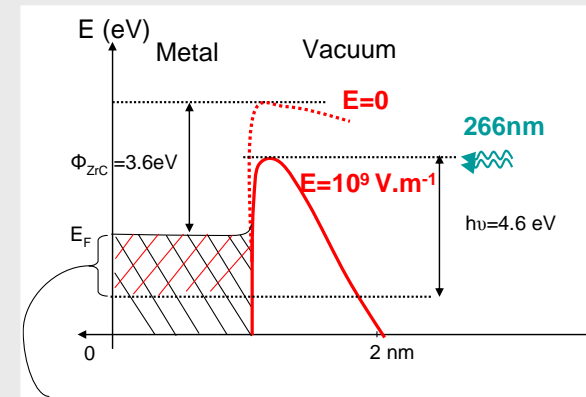


$r_{\text{tip}} \sim 30 \mu\text{m} ; \text{QE} = 10^{-4}$
 $r_{\text{tip}} \sim 10 \mu\text{m} ; \text{QE} = 10^{-3}$





Combination of Fowler-Nordheim and Schottky Dependence



$$Q(V_{Tip}) = e \cdot N_{Photons} \cdot \left(\frac{1}{E_F}\right)^{3/2} \left[E_F^{3/2} - \left(E_F + \phi - h\nu - \sqrt{\frac{q^3 \beta V_{tip}}{4\pi\epsilon_0}} \right)^{3/2} \right]$$

$$+ 1,4 \cdot 10^{-6} \cdot S \cdot \exp\left(\frac{10,4}{\sqrt{\phi}}\right) \cdot \beta^2 \cdot V_{tip}^2 \exp\left(\frac{-6,44 \cdot 10^7 \cdot \phi^{3/2}}{\beta V_{tip}}\right)$$

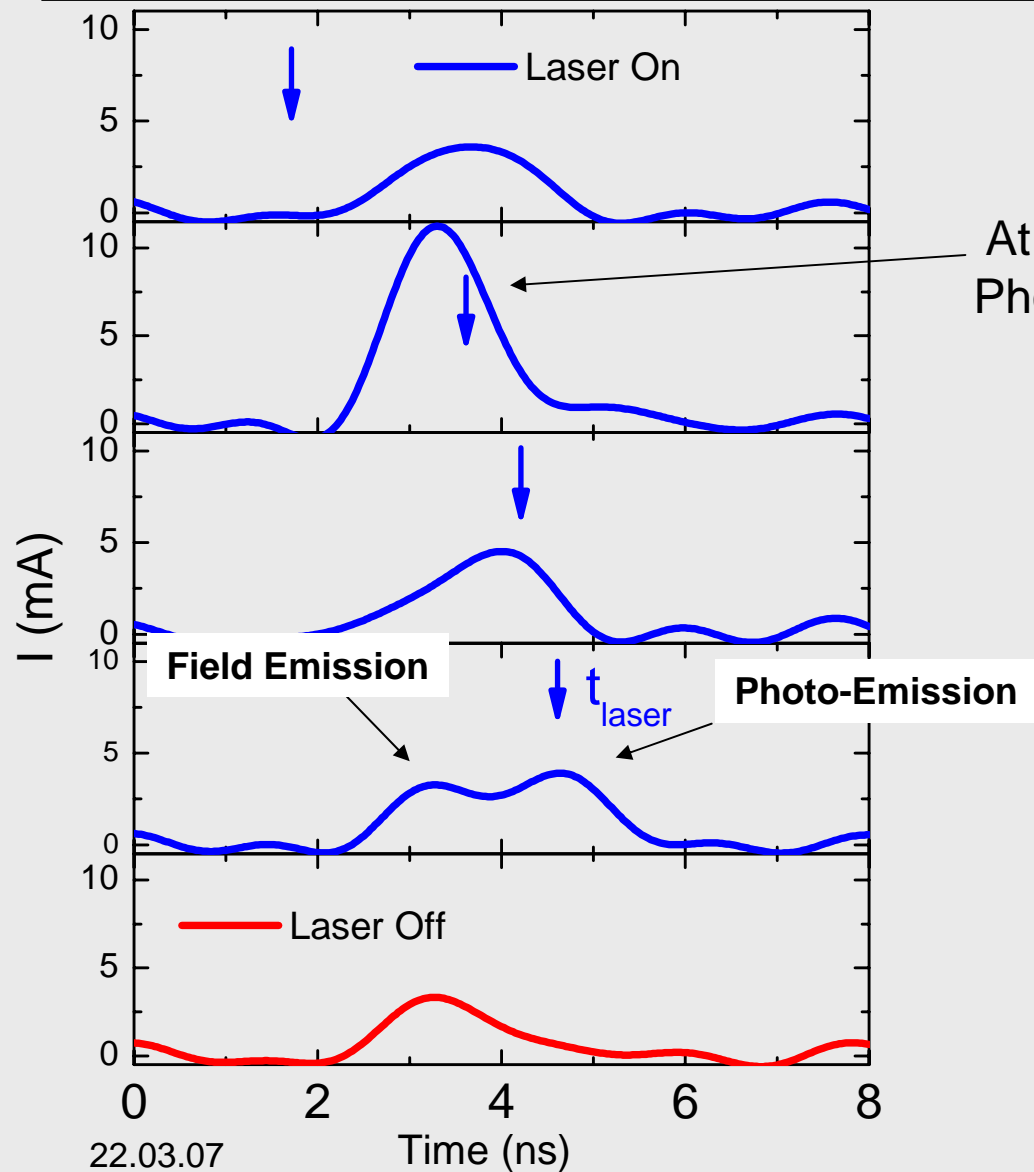


Photo-emission term



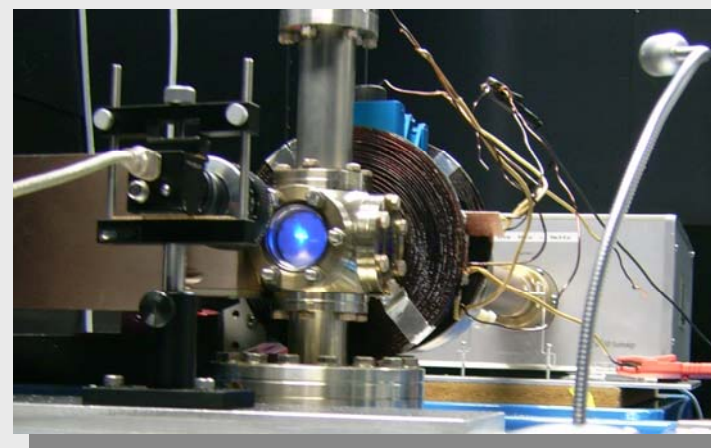
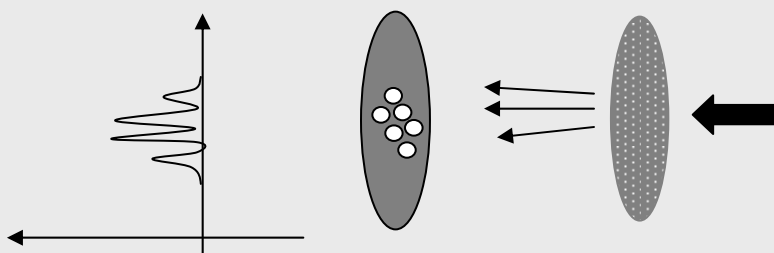
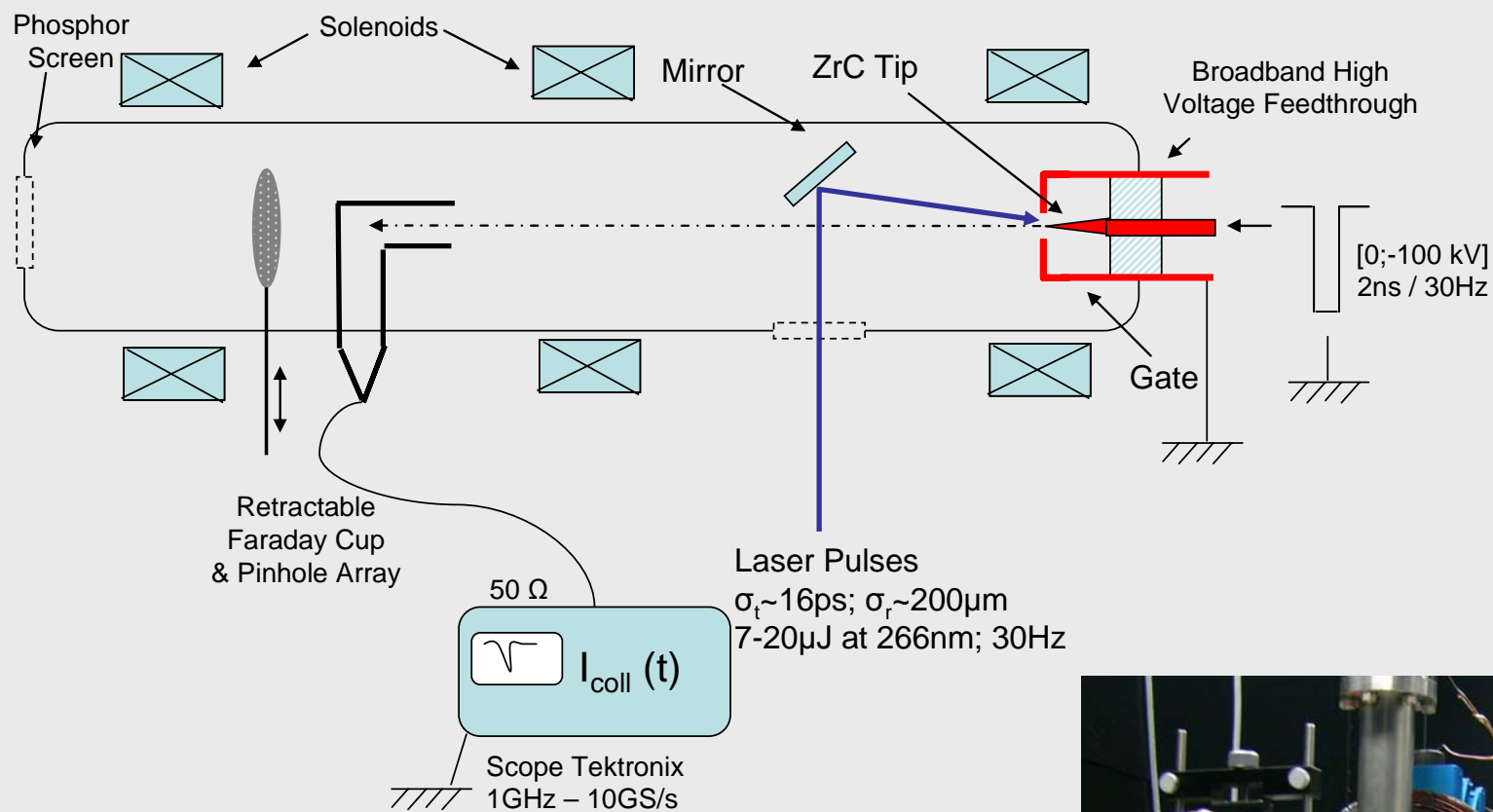
Field Emission term

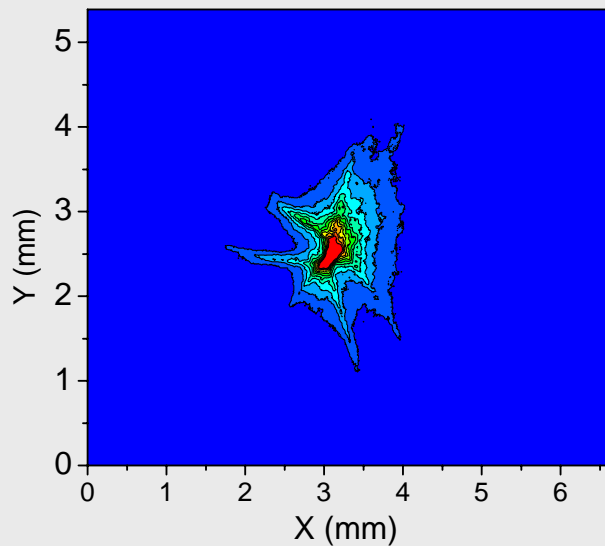
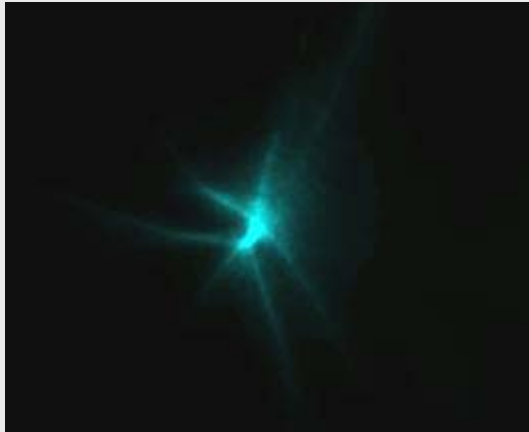
Delay Voltage Pulse / Laser Pulse



At Synchronisation:
Photo-field Emission

Laser: $11\mu\text{J}$ / 30Hz / 266nm
 / 10^{-9} Torr; Scope 1GHz
 Setup: ZrC tip + 2mm aperture + Focus Elect;
 $V_{DC}=0\text{V}$; $V_{solenoid}=14\text{V}$; $V_{Tip}=-40\text{kV}$

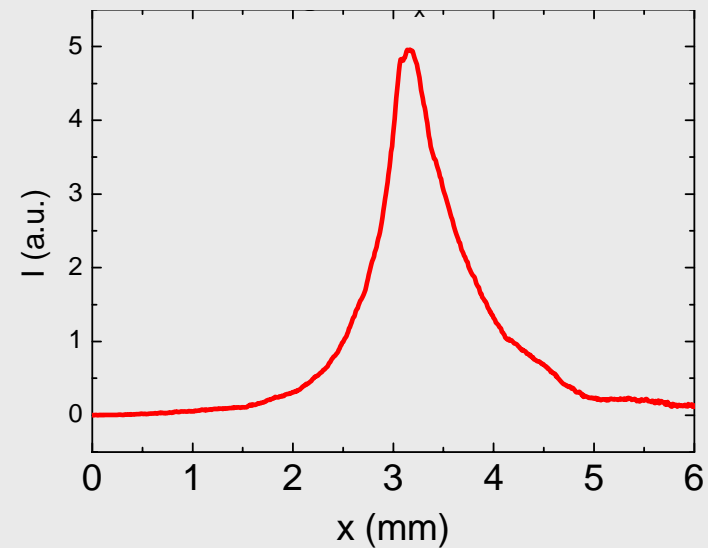


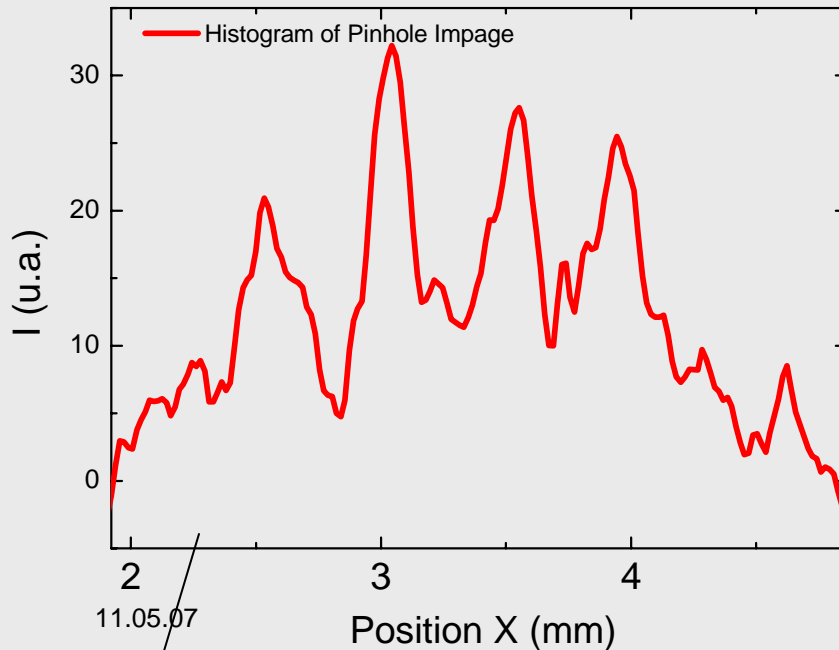
Electron Beam Spot
(Phosphor Screen)

Laser: $11\mu\text{J}$ / 30Hz / 266nm
/ 10^{-9} Torr; Scope 1GHz
Setup: ZrC tip + 2mm aperture + Focus Elect;
 $V_{\text{DC}}=0\text{V}$; $V_{\text{solenoid}}=14\text{V}$; $V_{\text{Tip}}=-40\text{kV}$

$11\mu\text{J}$ at 266nm
 $Q=12\text{pC}$; 40 keV
FWHM = $740\mu\text{m}$

Electron Beam Profile



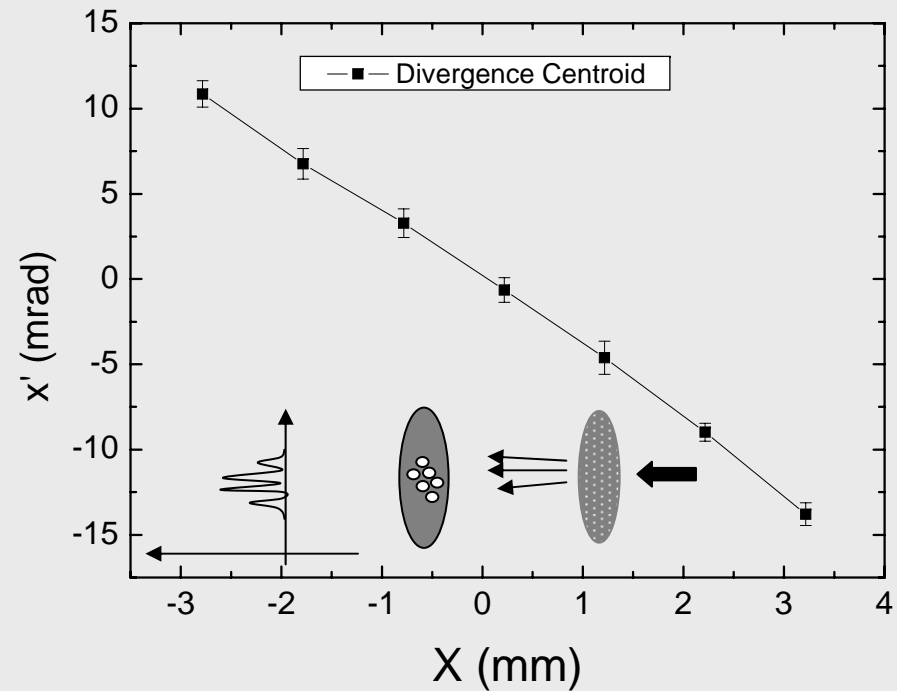


Weak Signal after Pinhole Array

$$\epsilon \text{ (mm.mrad)} = 1.3 \text{ (+/- 0.2)}$$

Laser: $2.3\mu\text{J} / \sigma_z=16\text{ps} / \sigma_r=75\mu\text{m} / 30\text{Hz} / 266\text{nm}$
 ZrC tip: $V_{\text{Tip}}=-27\text{kV}$

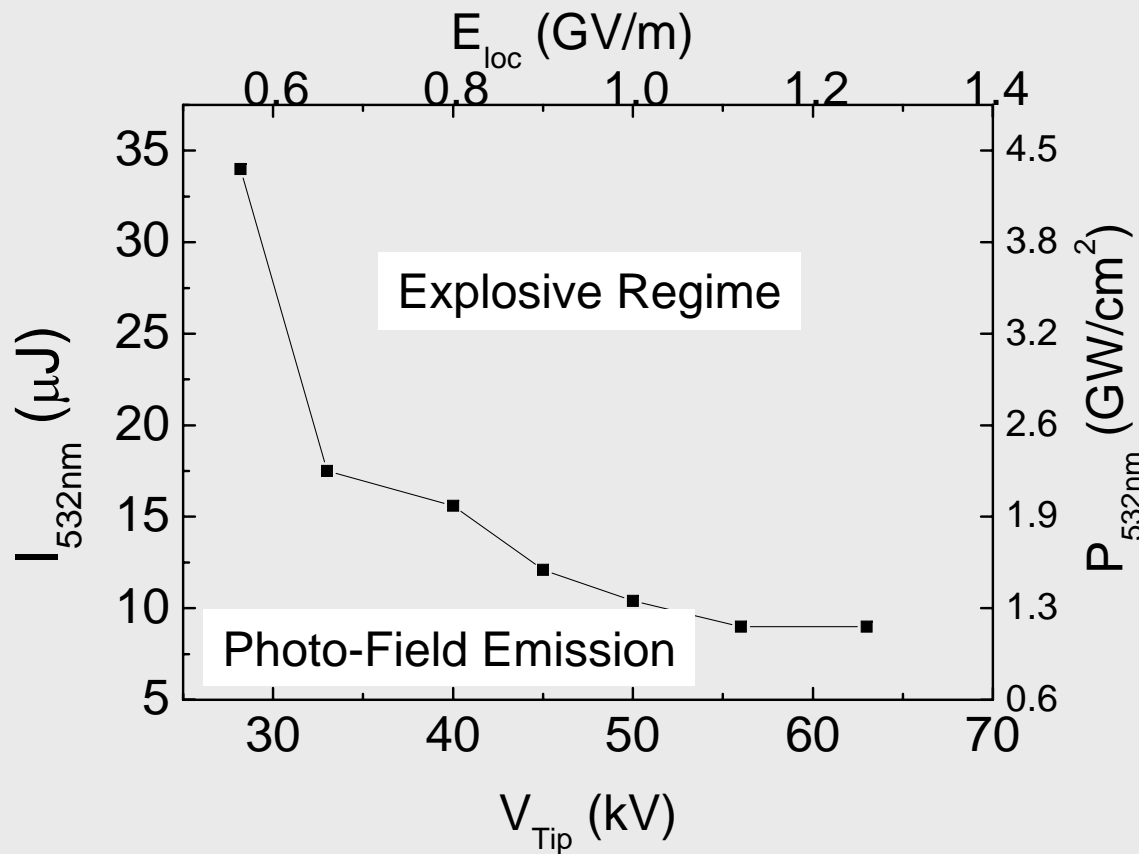
12.06.07 – Lund Workshop



Normalized Emittance (27 keV; 20pC)

$$\epsilon_n = \beta\gamma\epsilon$$

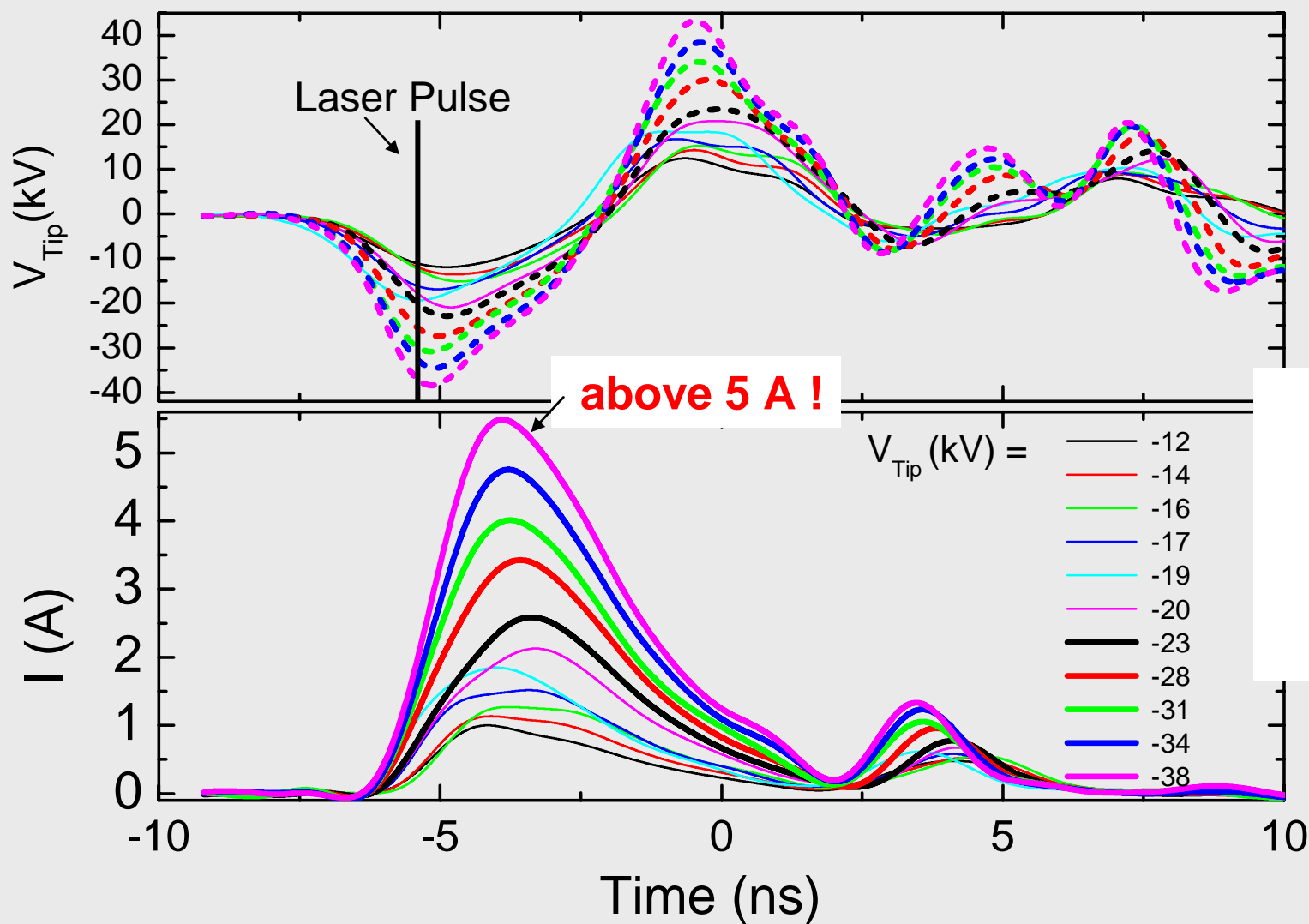
$$\epsilon_n = 0.5 \pm 0.1 \text{ mm.mrad}$$



High E_{Field}
 ↓
 easier to trigger Plasma

EEE numbers:
 $J \sim 10^8 \text{ A}/\text{cm}^2$
 Losses: $10^{-8} \text{ g}/\text{C}$
 $E_{\text{EEE}} > 10^4 \text{ J}/\text{g}$
 $P \sim 10^9 \text{ Pa}$

Litterature: $I_{\text{Ablation}} \sim 20 \text{ GW}/\text{cm}^2$ for Copper when No Gradient



**Explosive
Electron
Emission
=
Stationary
Process**

Laser Pulse: 532nm; 20μJ; 16ps; 10Hz; $P_{\text{Laser}} > 1 \text{ G W/cm}^2$

Conclusion :

FEA Technology: Great Potential: No laser needed
PSI Status: All metal single gated FEA
Issues: Double gate fabrication; Uniformity

Needle Cathode + Laser: Approaching PSI FEL requirements (1A; 0.5mm.mrad)
Issues: Synchronization and Pointing stability

Laser induced Plasma Emission: Very Intense; Stable
Issue: Control of bunch length